

NITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Confirmation No. 6344

Yoshio YANASE et al.

Docket No. 2001-0615A

Serial No. 09/856,982

Group Art Unit 2877

TC 2800 MAIL ROOM

Filed May 30, 2001

Examiner Sang H. Nguyen

METHOD FOR INSPECTING SEMICONDUCTOR WAFER SURFACE

<u>PETITION FOR EXTENSION OF TIME</u>

Assistant Commissioner for Patents. Washington, DC 20231

THE COMMISSIONER IS AUTHORIZED TO CHARGE ANY DEFICIENCY IN THE FEES FOR THIS PAPER TO DEPOSIT **ACCOUNT NO. 23-0975**

Sir:

Petition hereby is made for a two month extension of time to respond to the communication of October 15, 2002.

The fee of \$410.00 is

- submitted herewith. (X)
- to be charged to Deposit Account No. 23-0975. A duplicate copy of this Petition () is enclosed.
- Small entity status of this application is established by a Small Entity Status 0 Assertion which
 - () is enclosed.
 - 0 has been previously submitted.

Respectfully submitted,

Yoshio YANASE et al.

Ву

Joseph M. Gorski Registration No.46,500 Attorney for Applicants

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